

GS08 Atomic and close-to-atomic scale manufacturing

GS08-01 Fabrication of atomic-scale structures on gallium arsenide by tip induced local oxidation and post etching

Yangyang Li, Jinyan Tang, Mao Peng and Yuan-Liu

GS08-02 In-process monitoring of current for quality control in scanning probe oxidation lithography of atomic and close-to-atomic structure

Mao Peng, Jinyan Tang, Yangyang Li and Yuan-Liu Chen

GS08-03 Atomic and Close-to-atomic Scale Manufacturing of Large-scale Solid-state Nanopore Array

Jufan Zhang, Hongshuai Liu, Boyuan Pang and Fengzhou Fang